



## ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	PLANARIZED SEMICONDUCTOR INTERCONNECT TOPOGRAPHY AND METHOD FOR POLISHING A METAL LAYER TO FORM INTERCONNECT						
Application Number:		09/779123					
Confirmation Number:		9269					
First Named Applicant:		Anantha Sethuraman					
Attorney Docket Number:		5298-02502					
Art Unit:		2823					
Examiner:		Hsien-Ming Lee					
Search string:		( 5958794 or 5972124 ).pn.					
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
<i>Lee</i>	1	5958794	1999-09-28	Bruxvoort et al.			
<i>Lee</i>	2	5972124	1999-10-26	Sethuraman et al.			
Signature							
Examiner Name				Date			
<i>Hsien Ming Lee</i>				<i>4/20/04</i>			